IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Filing Date February 13, 2002 Inventor Shenlin Chen et al. Assignee Micron Technology, Inc. Examiner Huynh, Y. Methods of Forming a Capacitor Structure Title:

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References –See Attached Form PTO-1449

The Examiner's attention is directed to the references which are listed on the attached Form PTO-1449, copies of which are attached. No admission is made regarding whether all the submitted references are prior art.

Citation of the referenced art is respectfully requested.

Respectfully submitted,

AU6 2 7 2003